

FORM PTO-1449	SERIAL NO. 10/714,252 To be assigned	CASE NO. 11470-4
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT	FILING DATE To be assigned	GROUP ART UNIT To be assigned 2018
(use several sheets if necessary)		APPLICANT(S): SNOWDON et al.

REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS/ SUBCLASS	FILING DATE
TL	A1	6,314,019 B1	11/6/2001	Kuekes et al.		
	A2	6,248,674 B1	6/19/2001	Kamins et al.		
	A3	6,128,214	10/3/2000	Kuekes et al.		
	A4	5,155,826	10/13/1992	Fadem		
	A6	4,490,783	12/25/1984	McDonough et al.		
	A5	4,807,218	02/21/1989	Gerber		

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS/ SUBCLASS	TRANSLATION YES NO
TL	A6	PCT/GB01/00222	6/12/2001	European Patent Office - PCT Written Opinion		

EXAMINER INITIAL	OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)	
TL	A7	Batzill, M., et al., "Preferential Sputtering Induced Stress Domains and Mesoscopic Phase Separation on CaF ₂ (111)," <i>Physical Review Letters</i> , Volume 85, Number 4, pp. 780-783, (July 24, 2000).
TL	A8	Facsko, S., et al., "Formation of Ordered Nanoscale Semiconductor Dots by Ion Sputtering," <i>Science</i> , Volume 285, pp. 1551-1553, (September 3, 1999).
TL	A9	Wissing, M., et al., "An Apparatus for Glancing Incidence Ion Beam Polishing and Characterization of Surfaces to Angstrom-Scale Root-Mean-Square Roughness," <i>Rev. Sci. Instrum.</i> , Volume 67, Number 12, pp. 4314-4320, (December 1996).

EXAMINER <i>Thao</i>	DATE CONSIDERED 9/04/05
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.